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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICATION SERIAL NO. Filed Concurrently Herewith
FILING DATE Filed Concurrently Herewith
INVENTORSHIP Weimin Li et al.
ASSIGNEE Micron Technology, Inc.
GROUP ART UNIT Unknown
EXAMINER Unknown
ATTORNEY'S DOCKET NO. MI22-1208
TITLE: Low k Interlevel Dielectric Layer Fabrication Methods

INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56. Copies of documents listed on the Form PTO-1449 are enclosed, except that copies of the listed pending applications are not enclosed.

No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 8/30/99

Inventor: Weimin Li

Dated: 8/30/99

Inventor: Zhiping Yin

Dated: 8/30/99

Inventor: William Budge

Dated: 9/1/99

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